INDIAN INSTITUTE OF SCIENCE EDUCATION AND RESEARCH

PUNE

CLARIFICATION ON TENDER NUMBER - IISER-PUR-0438-18

ITEM DESCRIPTION- PROCUREMENT OF SPUTTERING CUM THERMAL EVAPORATION SYSTEM.

Refer our Press Tender Notice No.IISER/S&P/8/2018 dated 24.8.2018 for procurement of Sputtering Cum thermal evaporation system**.** Tender Reference Number – IISER-PUR-0438-18.

Pre-Bid meeting was held on August 30th , 2018 at 11.00 am and minutes of meeting is as under.

At the outset, the Chairman welcomed all the Members and the representative of the Prospective Bidders and briefed in general the scope of the Project and thereafter requested Assistant Registrar (S&P) to brief the vendors on the salient features of the commercial terms and the indenting Officer to read out the clarification sought by the Prospective Bidders and replied thereto as detailed in Annexure -II

The representatives present were satisfied with the replies given and it was informed that the corrections / additons / clarifications given, as discussed during the Pre-Bid Conference would be hosted on the website of IISER Pune and all the Prospective Bidders are required to take cognizance of the proceedings of the Pre-Bid Conference before submitting their bids as stipulated in the Bidding Documents.

The other terms & conditions of the notice issued on our IISER website www.iiserpune.ac .in will remain unchanged. No more correspondence in this regard will be entertained

The meeting ended with vote of thanks to the Chair

Sd/-

30.8.2018 Assistant Registrar (S&P)

ANNEXURE -II

IISER PUNE

PRE-BID CONFERENCE FOR PROCUREMENT OF SPUTTERING CUM THERMAL EVAPORATION SYSTEM

TECHNICAL QUERIES AND CLARIFICATION

TENDER NUMBER - IISER-PUR-0438-18 DATE : 30.8.18

S.No	Query/Clarification Sought	Clarification / Amendment
1	**Chapter 4, Page No – 20, Point 4, Deposition thickness** Clarification regarding "removing the specification on deposition thickness "	**Chapter 4, Page No – 20, Point 4, Deposition thickness Point 4 is amended with new specification.** The specification number 4 'deposition thickness' is removed and a new specification about thickness controller is added. The new specification number 4 reads "Thickness controller: A thickness controller with feedback loop should be provided."

2	**Chapter 4, Page No – 20, Point 5, Substrate Holder** Clarification regarding "replacing the word substrate holder with multiple substrate holder"	**Chapter 4, Page No – 20, Point 5, Substrate Holder is amended as.** Specification number 5: The word substrate holder is replaced with multiple substrate holder The revised specification number 5 reads: "Multiple substrate holder"
3	**Chapter 4, Page No – 20, Point 5, Substrate Holder** Clarification regarding "specifying the active area of deposition"	**Chapter 4, Page No – 20, Point 5, Substrate Holder. A new specification is added as 5d.** The new specification number 5d reads: "The active area of deposition should be at least 2 x 2 inches for thermal and sputtering."
4	**Chapter 4, Page No – 21, Point 7e, Vacuum chamber** Clarification regarding "specifying the definitive number for ultimate vacuum, and whether the ultimate vacuum is before or during evaporation"	**Chapter 4, Page No – 21, Point 7e, Vacuum chamber Is amended to** The revised specification 7e reads: "The ultimate vacuum before evaporation should be < 5 x 10^{-7} mbar or better."
5	**Chapter 4, Page No – 21, Point 8, Vacuum pumps, lines and valves** Clarification regarding "specifying some suppliers of turbo pump"	**Chapter 4, Page No – 21, Point 8, Vacuum pumps, lines and valves. A new specification is added to point 8.** The revised specification 8 includes "The turbo pump should be from either Edwards, Leybold, or Pfeiffer, having established service centers in India."
6	**Chapter 4, Page No – 21, Point 8, Vacuum pumps, lines and valves** Clarification regarding "inclusion of pressure control valve"	**Chapter 4, Page No – 21, Point 8, Vacuum pumps, lines and valves. A new specification is added in point 8.** The revised specification 8 includes "Appropriate pressure control valve should be provided."

7	**Chapter 4, Page No – 21, Point 10a, Magnetron sources** Clarification regarding "specifying some suppliers of magnetron sources"	**Chapter 4, Page No – 21, Point 10a, Magnetron sources. A new specification is added in point 10a.** The revised specification 10a includes "All the magnetron sources for sputtering should be from established suppliers with service centers in India."
8	**Chapter 4, Page No – 22, Point 11a, Power Supplies** Clarification regarding "specifying some suppliers of power supply"	**Chapter 4, Page No – 22, Point 11a, Power Supplies A new specification is added in point 11a.** The revised specification 11a includes " All the power sources (2 DCs and 1 RF) should be from established suppliers with service centers in India"
9	**Chapter 4, Page No – 21, Point 11e, Power Supplies** Clarification regarding "bias sputtering"	**Chapter 4, Page No – 21, Point 11e, Power Supplies Specification 11e amended to.** Bias sputtering of substrates is removed. The revised specification number 11e reads "Appropriate switching systems should be provided which is capable of switching power supplies between both magnetrons as well as to switch the power from RF to DC (thermal evaporator) or DC (thermal evaporator) to RF"
10	**Chapter 4, Page No – 22, Point 14a, Mass Flow Control System** Clarification regarding "N_2 gas mass flow controller"	**Chapter 4, Page No – 22, Point 14a, Mass Flow Control System - Specification 14a amended to:** One Mass flow controller for N_2 gas is removed from the specification. The revised specification number 14a reads "A Mass flow control (MFC) for Ar (2-100 sccm) should be provided."

11	**Chapter 4, Page No – 22, Point 14b, Mass Flow Control System** Clarification regarding "N_2 gas mass flow controller"	**Chapter 4, Page No – 22, Point 14b, Mass Flow Control System. Specification 14b revised.** A port for a second gas flow for future upgradation should be provided. The revised specification number 14b reads "A port for a second gas flow for future upgradation should be provided. Digital display to monitor the flow of two gases with proper controller (manual and software controlled) should be provided."

ANNEXURE -III

IISER PUNE

PRE-BID CONFERENCE FOR PROCUREMENT OF SPUTTERING CUM THERMAL EVAPORATION SYSTEM

COMMERCIAL QUERIES AND CLARIFICATION

TENDER NUMBER - IISER-PUR-0438-18 DATE : 30.8.18

S.No	Query/Clarification Sought	Clarification / Amendment
	----------NIL----------	----------NIL----------